

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : **Hong Hocheng,** Date : **Oct. 23, 2003**
Yun-Liang Huang
Serial No. : Group Art Unit :
Filed :
For : **A METHOD FOR DETECTING THE ENDPOINT OF A**
CHEMICAL MECHANICAL POLISHING (CMP) PROCESS

Honorable Commissioner of Patents
and Trademarks
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a completed Form PTO-1449 and copies of the pertinent parts of the references cited thereon. Comments on any non-English-language references (if any) pursuant to Rule are submitted herewith.

Respectfully submitted

Applicants(s):



Encl: PTO-1449 & References

FORM PTO-1449 (Substitute)				ATTY. DOCKET NO. 03219-JRS		SERIAL NO.	
LIST OF PRIOR ART CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				APPLICANT Hong Hocheng, Yun-Liang Huang			
				FILING DATE		GROUP	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APROPRIATE
	AA	5,196,353	Mar. 23, 1993	Sandhu et al.	437	8	Jan. 3, 1992
	AB	5,597,442	Jan. 28, 1997	Chen et al.	156	626.1	Oct. 16, 1995
	AC	5,643,050	Jul. 1, 1997	Chen	451	10	May 23, 1996
	AD	5,647,952	Jul. 15, 1997	Chen	156	636.1	Apr. 1, 1996
	AE	5,722,875	Mar. 3, 1998	Iwashita et al.	451	8	May 30, 1996
	AF	6,007,408	Dec. 28, 1999	Sandhu	451	41	Aug. 21, 1997
	AG	6,077,783	Jun. 20, 2000	Allman et al.	438	691	Jun. 30, 1998
	AH	6,150,271	Nov. 21, 2000	Easter et al.	438	692	Sep. 10, 1998
FOREIGN PATENT DOCUMENTS							
	AI						
	AJ						
	AK						
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AL						
	AM						
	AN						
	AO						
EXAMINER				DATE CONSIDERED			
<i>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</i>							